



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Dapeng Wang

Serial No.: 10/729,112

Filed: December 5, 2003

For: CHEMICAL MECHANICAL
POLISHING APPARATUS AND
METHODS FOR CHEMICAL
MECHANICAL POLISHING

Confirmation No.: 3169

Examiner: R. Rose

Group Art Unit: 3723

Attorney Docket No.: 2269-3579.2US
(98-0062.02/US)

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AMENDMENT PURSUANT TO 37 C.F.R. § 1.312(a)

Mail Stop ISSUE FEE
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Please amend the above-referenced application as follows:

Amendments to the Title appear on page 3 of this paper;

Amendments to the Specification begin on page 4 of this paper;

A listing of the Claims are set forth in the listing of the claims that begins on page 7 of this paper;

Corrections to the Drawings are summarized on page 14 of this paper, with replacement sheet and annotated sheet showing the corrections enclosed herewith; and

Remarks start at page 15 of this paper.

IN THE TITLE:

The title has been amended herein. Pursuant to 37 C.F.R. §§ 1.121 and 1.125 (as amended to date), please amend the title as follows:

DEFORMABLE PAD-CHEMICAL MECHANICAL POLISHING APPARATUS AND
METHODS FOR CHEMICAL MECHANICAL POLISHING